



WMP-IFT-699

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Date:

April 12, 2004

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Confirmation No. 6635

Applicant

: Matthias Stecher et al.

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Examiner

: Mark V. Prenty

Title:

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Hon. Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

## RESPONSE

## Sir:

In response to the Office action dated November 10, 2003, please consider the following remarks or arguments:

Remarks/Arguments begin on page 2 of this paper.

An **Appendix** including the document Schwalke et al ("Ultra-Thick Gate Oxides: Charge Generation and Its Impact on Reliability," presented at the 10<sup>th</sup> WODIM, Munich November 13-15, 2000) is attached following page 7 of this paper.

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